



Photocathodes for Polarized Beams

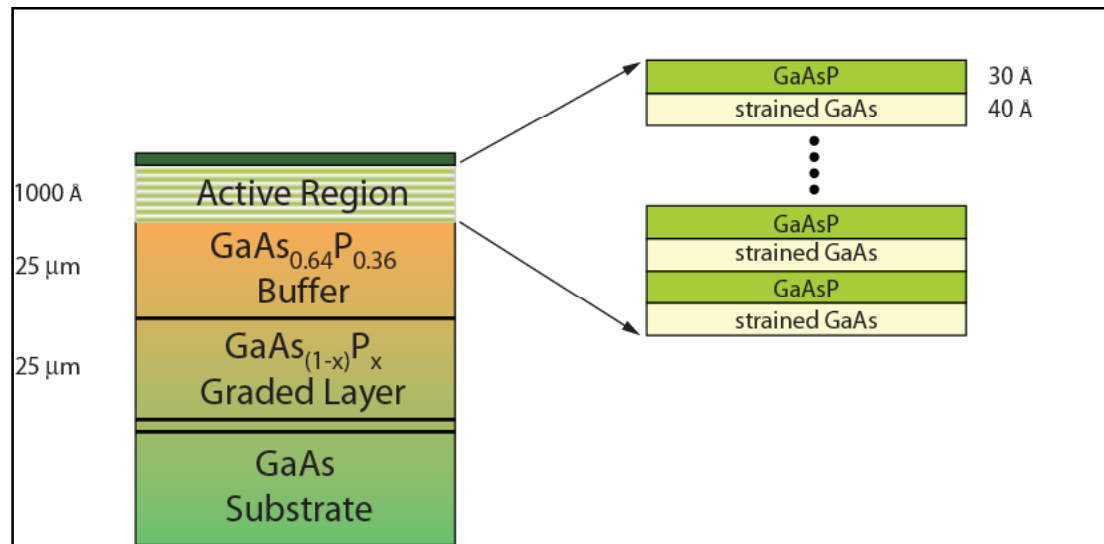
Takashi Maruyama
SLAC

ILC e- source KOM, September 24-25, 2007



Photocathodes

Baseline design: strained layer superlattice GaAs/GaAsP
Polarization ~ 85 - 90 % ,QE 1% maximum, 0.3-0.5%
routinely



High gradient p-doping increases QE and reduces surface charge limit:

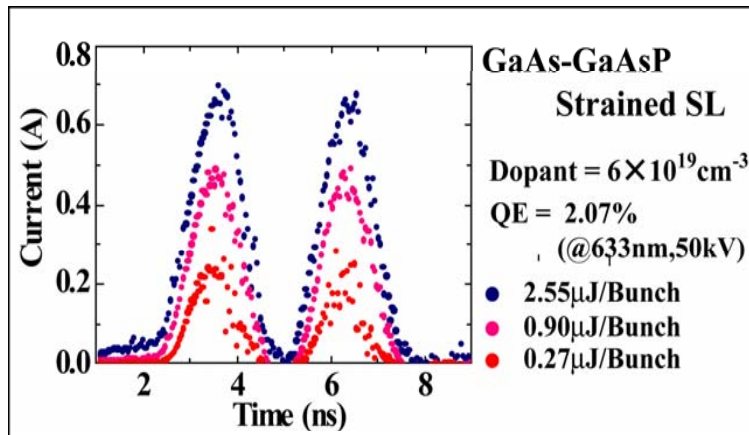
$$5 \times 10^{19} \text{ cm}^{-3} \rightarrow 5 \times 10^{17} \text{ cm}^{-3}$$



Surface Charge Limit

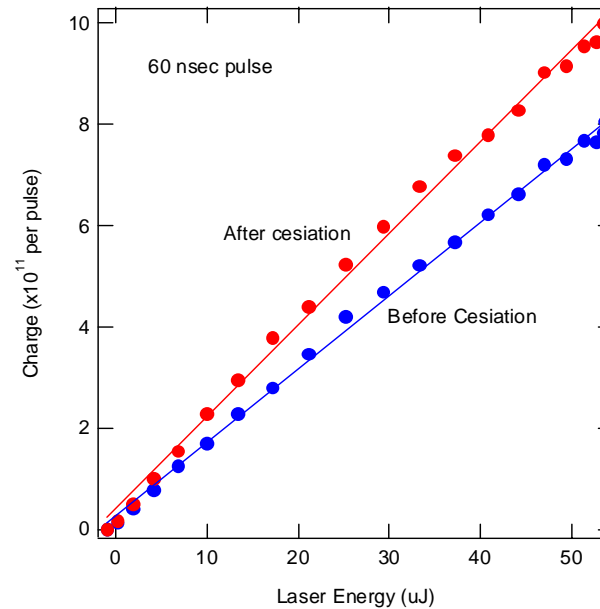
Surface charge limit has not been studied under the ILC conditions

Nagoya



p-p : 2.8ns,
bunch-width : 0.7ns
Charge: 1nC/bunch

SLAC



1×10^{12} e- in 60 ns
 $\rightarrow 4.5 \times 10^{12}$ e- in 270 ns
($\times 3$ NLC train charge)

No charge limit in < 300 ns.

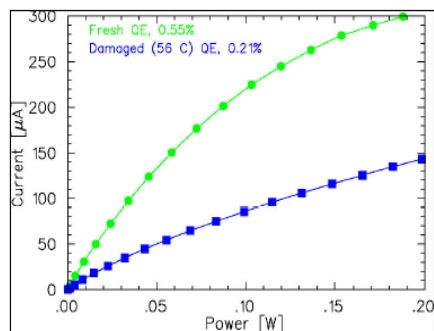


Surface Charge Limit seen in CW machines

Poelker (PSTP07)

But QE not constant...

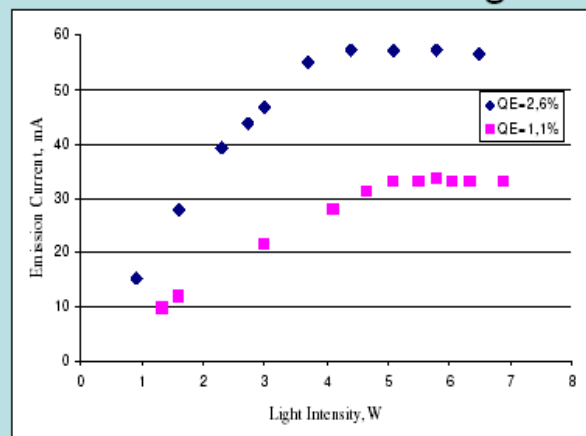
...when surface is damaged or dirty



Surface charge limit, not just a problem for pulsed machines

Aulenbacher (Spin06)

Experimental conditions/results 4: surface charge limit



emitted area
 $\pi \cdot (1.05\text{mm})^2 \approx 3.5 \text{ mm}^2$
hole concentration
 $2 \cdot 10^{19} \text{ cm}^{-3}$

Current density is presently limited to 1.6 A/cm^2 .

57 mA in $100 \mu\text{s}$ long pulses at 100 Hz repetition rate.

$Q = 5.7 \mu\text{C}$ per Impulse



03/10/2006

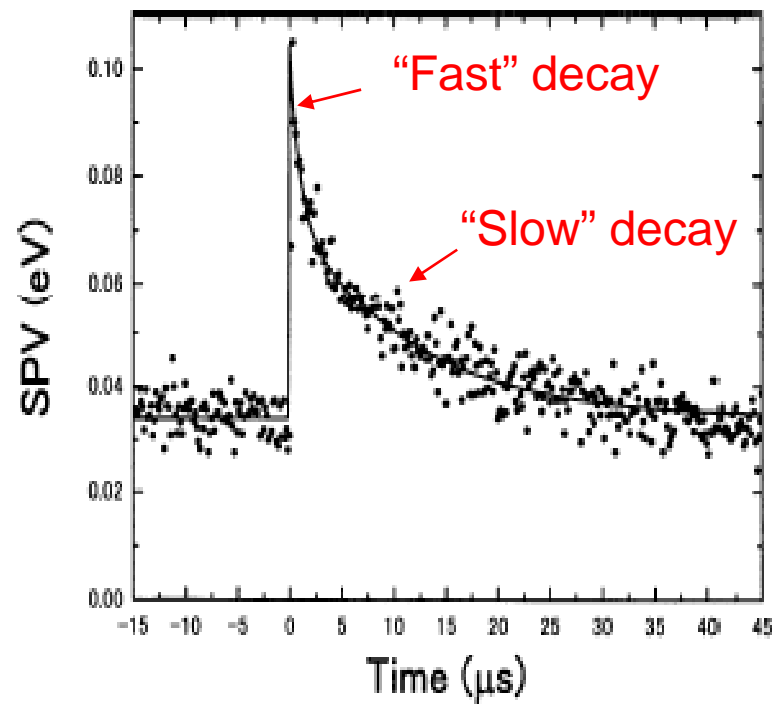
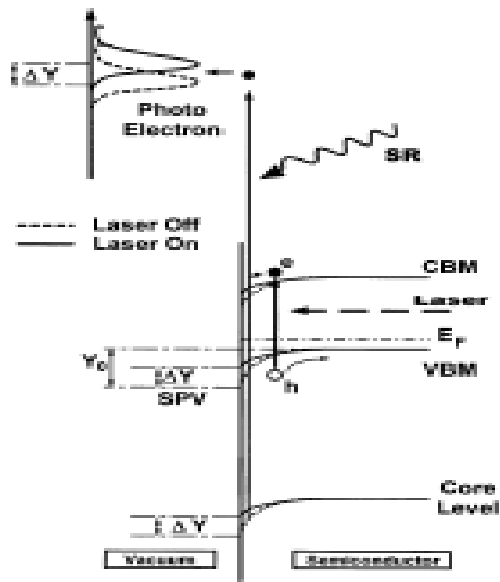
Small influence of SCL on lifetime measurements at currents $< 10 \text{ mA}$ if $q_e > 1\%$.





“Fast” and “Slow” Photovoltage Decay Time

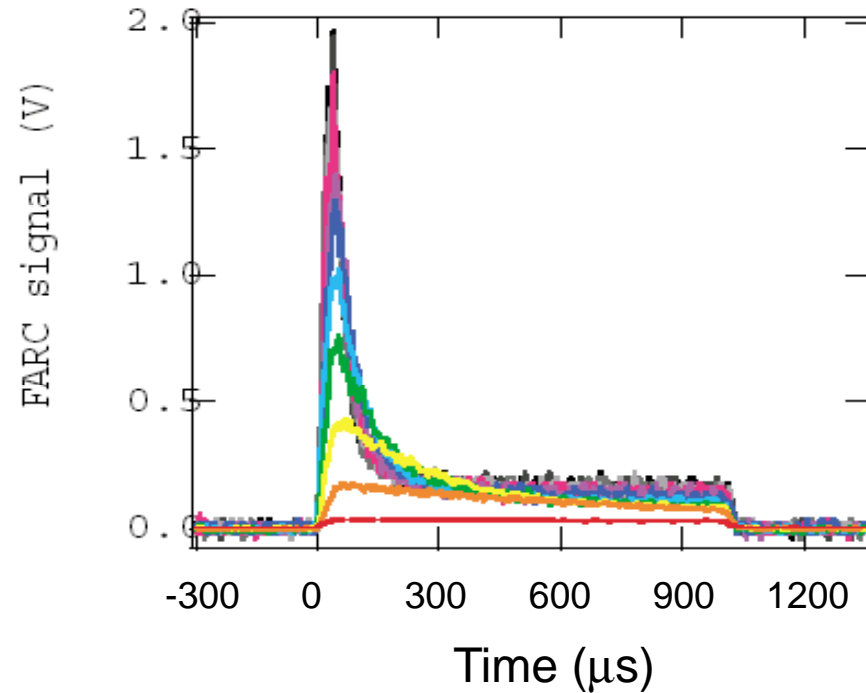
S. Tanaka et al. Surface Review and Letters, 9, 1297 (2002)





ILC Train Extraction

- Need to demonstrate ILC train extraction as soon as possible.
- ILC laser development should be highest priority.



ILC train may look like this.

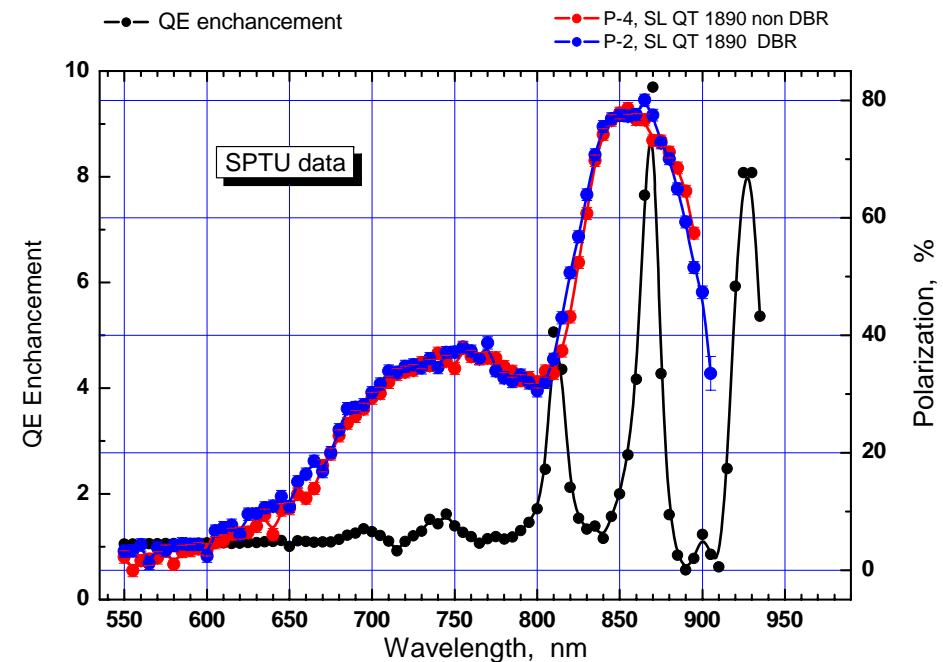
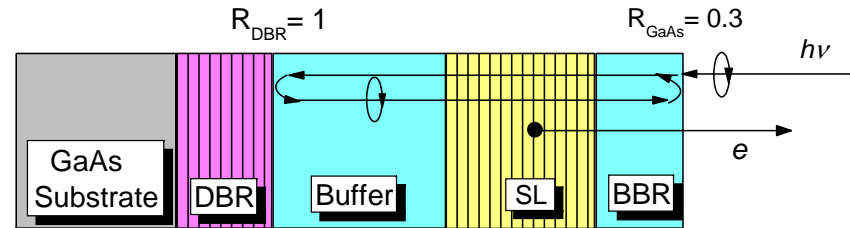


Lower heat-cleaning temperature

- Cathode needs high temperature ($\sim 600^\circ\text{C}$) heat-cleaning to achieve high QE.
 - Dopant diffusion \rightarrow surface charge limit
 - Try carbon doping
 - Surface damage/surface states \rightarrow surface charge limit
- Lower heat-cleaning temperature to $\sim 450^\circ\text{C}$ and achieve high QE
 - Atomic hydrogen cleaning

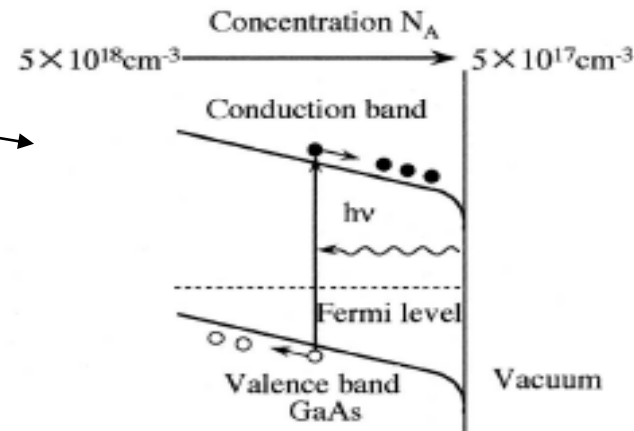
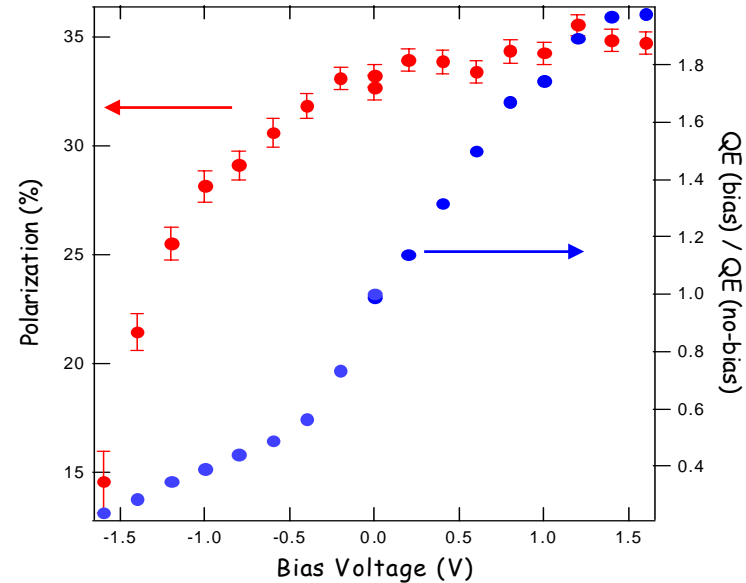
Gerchikov (PSTP07)

- ILC laser may not have enough energy.
 - 5 $\mu\text{J}/\text{pulse}$ is tough.
- DBR was first introduced by Nagoya group.
- $\times 10$ QE enhancement has been achieved.
- Structure gets more complex, and matching pol max and QE max is not quite reproducible.



Bias enhancement of QE

- QE enhancement is possible when the cathode front surface is positively biased.
- Polarization increases as the electron drift time gets shorter.
- External bias
 - SBIR with Saxet Surface Science.
- Internal bias
 - Gradient doping
 - W. Zhen et al., JJAP 38, L41 (1999) (Photoluminescence study)
 - Gradient composition
 - SBIR Phase I with SVT





Polarization improvements

- GaAsP/GaAs strained superlattice
 - Superlattice parameter optimization
 - Doping profile optimization
- New structures
 - InAlGaAs/AlGaAs strained superlattice
 - In collaboration with St. Petersburg group.
 - AlGaAsSb/AlGaAs strained superlattice
 - SBIR Phase I with SVT Associates

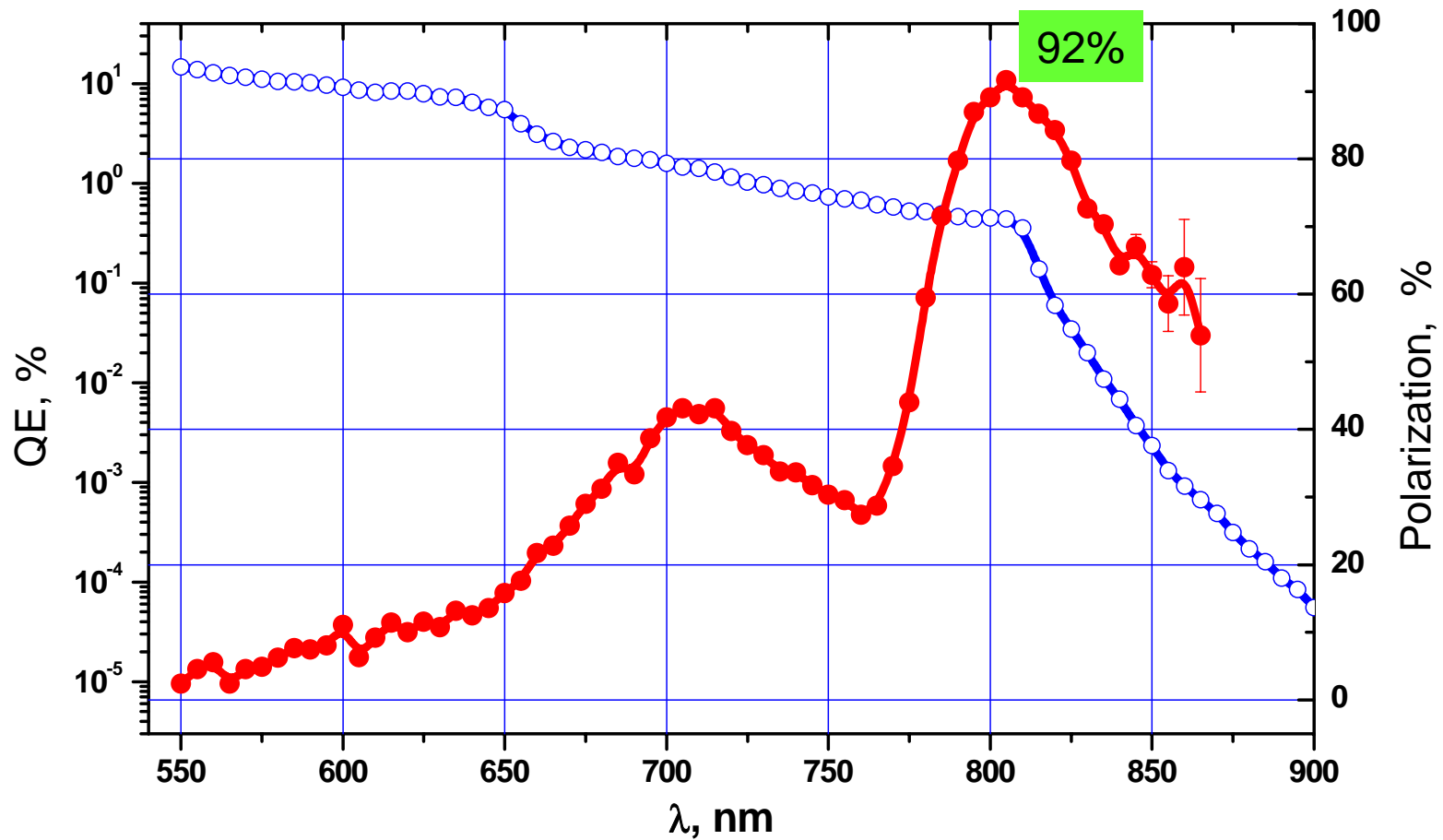


SL $\text{In}_{0.155}\text{Al}_{0.2}\text{Ga}_{0.645}\text{As}(5.1\text{nm})/\text{Al}_{0.36}\text{Ga}_{0.64}\text{As}(2.3\text{nm})$, 4 pairs

Mamaev (PSTP07)

—○— QE

—●— Polarization



Spectra of electron emission: Polarization **P** and Quantum Efficiency **QE**



Wafer growers

- SLC single-strained wafers
 - All grown at Spire/Bandwidth Semiconductors
 - Wafer quality varied, each wafer characterized, and good wafers selected.
- GaAsP/GaAs strained superlattice
 - Nagoya University
 - SVT Associates
- Need to find wafer grower
 - SVT Associates may not be in business for long time.
 - Find University group?
 - Photocathode wafers are not industry standard.
 - Takes time to optimize growth



Wafer Characterization

- What is grown is not always what is designed.
- Polarization and QE alone do not characterize the structure.
- Ability to characterize wafers is important.
 - Photoluminescence
 - X-ray diffraction
 - Surface analyses: XPS, EDX, SIMS